

In the Claims

Claims 1 – 10 (Cancelled)

11. (Currently Amended) An organic EL device manufacturing method comprising the steps of:

(a) positioning an integrated mask and a single substrate to be subjected to a deposition process in a deposition chamber using alignment marks formed on said integrated mask and said single substrate,

wherein said integrated mask comprises:

(a-1) a plurality of deposition masks each of which has an array of deposition apertures formed in accordance with a deposition pattern and alignment marks,

(a-2) a base plate which has a plurality of openings on which said deposition masks are arranged respectively, each of said deposition masks being arranged over a ~~separate~~ respective opening, and which has alignment marks,

(a-3) a plurality of engaging units provided on said base plate that engage and disengage each of said deposition masks such that the position of each deposition mask is adjusted relative to the base plate independently of the other deposition masks, and

~~(a-4) said alignment marks formed on said base plate, and~~

wherein said integrated mask is fabricated by the steps of:

[[(a-5)]] (a-4) detecting said alignment marks of said base plate and each of said deposition masks,

[[(a-6)]] (a-5) adjusting the relative position between said base plate and each of said deposition masks prior to engaging the integrated mask with the substrate by independently retaining and independently moving each of said deposition masks relative to said base plate, and

[[(a-7)]] (a-6) retaining each of said deposition masks on said base plate using said engaging units after adjusting of said relative position; and

(b) patterning a thin film layer in said deposition process using said integrated mask, thereby forming n said organic EL devices on said single substrate wherein n is an integer equal to or greater than 2.

12. (Currently Amended) An organic EL device manufacturing method according to claim 11, wherein said integrated mask is set up by retaining m said deposition masks on said base plate wherein m is an integer in the range of 2 to n and wherein m and k satisfy n = m x k,

where k is a number of said array of deposition apertures formed on said each deposition mask
and an integer in the range of 2 to n.

13. (Cancelled)
14. (Previously Presented) An organic EL device manufacturing method according to claim 11, wherein said thin film is an emitting layer or a metal electrode layer.